Alva's Institute of Engineering and Technology
Dept. of Electronics and Communication Engineering

We cordially invite you to the Inaugural function of

Two days workshop
On

"Micro electro mechanical systems"

President:	**Dr. M. Mohan Alva** Chairman, AEF, Moodbidri.
Chief Guest:	**Basavaraj Sheeparimatti**, Professor, Basaveshwara Eng. College Bagalkot
Guest of Honor:	**Sri. Vivek Alva,** Management Trustee, AIET, Moodbidri,
Date:	**16/01/2017 @ 9.30A.M**

Convener	Principal	HOD
Dr.D.V Manjunatha Sr. Professor, AIET, Moodbidri.	**Dr. Peter Fernandes** AIET, Moodbidri.	**Dr.D.V Manjunatha** Dept. of ECE, AIET, Moodabidri.

Workshopon"Microelectro mechanicalsystems for Research perspective"

Objectiveof theworkshop

The MEMS system exists today in many environments, agriculture, and automotive, medical,consumer, industrial and aerospace.Their potential for future tunneling into a broad range ofapplications is real, supported by progressive activities both by academia and industry in allstreamsofengineering.ThedevelopmentofMEMSisinherentlyinterdisciplinary,necessitating an understanding of the fabrication methods. This FDP aims at providing theessence of Microelectronics and Micro Electro Mechanical Systems design using COSMOLMultiphysics Tools focusing on all engineering streams, so that, the faculty who attends thisFDPshouldcome outwiththeirownprojectinMEMS.

Fig: Inaugural Function MEMS workshop

ThemultiphysicsnatureofMEMSdevicesrequiresthatasystemdesignerhasavastunderstanding and knowledge of these various branches of physics. Because some microscaleeffects are totally new or behave differently than at the macroscale, engineers require newsystem-design philosophies. They likely find it difficult to split one design into parts, which iscommon for

macroscale device,where one engineer can fully study the mechanics whileothers concentrate, for instance, on the electrical or thermal aspects. Thus the MEMS engineerisatruesystemsdesigner,handlingseveralphysicalphenomenasimultaneously—andCOMSOL Multiphysics and the MEMS Module can do the same. Most MEMS devices aremanufacturedusinglithography-basedmicrofabrication,atechnologythatthemicroelectronics industry has refined for highly integrated circuits. Thanks to these effortsthereare excellentmethodologiesandfacilitiesformassproduction.

MEMS workshop Session by Mr.BasavarajSheeparimatti,

Twodaysworkshopon**16/01/2017and 17/01/2017**"MicroElectroMechanicalSystem for Research perspective"wasorganizedTheinaugurationceremony wasgracedby thepresenceof Mr.BasavarajSheeparimatti,Professor,Basaveshwara Eng. College Bagalkot,Mr. PrashanthHanasi,Professor, Jai College , Belagavi,Mr.Rajesh, Engineer,STD Bengaluru Dr. DV Manjunatha, HOD Dept of ECE, Dr. Praveen J, DeanAcademics, AIET.Theinauguralsessionstartedwithawelcomeaddress byDr.DVManjunatha, Head of the Dept., ECE, AIET.Followed by this, the dignitaries on the dais lightedthe lamp and formally inaugurated the session. A formal introduction of the chief guest of thefunctionwasdonebyProf.Shruthikumari,AsstProf.fromthedeptofECE.